

Amendments to the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (currently amended) A chemical vapor deposition apparatus comprising:

a chamber having an inner space and top, bottom, and side wall;

a susceptor disposed in the chamber and supporting a substrate;

a diffuser partitioning the inner space of the chamber into first and second partitions and having an extension extended out from a boundary, wherein the extension of the diffuser is exposed to the inner space of the chamber; and

an insulating frame disposed between the side wall of the chamber and the diffuser, said insulating frame being disposed on an upper side of the extension of the diffuser and extending to and contacting the side wall of the chamber.

2. (original) The apparatus of claim 1, wherein the extension of the diffuser has an "L" shape.

3. (original) The apparatus of claim 1, wherein the diffuser comprises Al or stainless steel.

4. (original) The apparatus of claim 1, wherein the insulating frame comprises ceramic.

5. (original) The apparatus of claim 1, wherein the substrate comprises glass.

6. (original) The apparatus of claim 1, wherein the substrate is prepared for a liquid crystal display.

7. (original) The apparatus of claim 1, further comprising a blocking member for mixing and spreading the gas from the gas feed member before the gas passes through the holes of the diffuser.

8. (original) The apparatus of claim 1, wherein the diffuser is electrically powered and the susceptor is electrically grounded.

9. (previously presented) The apparatus of claim 1, further comprising: a gas feed member for supplying a gas into the chamber.

10. (previously presented) The apparatus of claim 1, wherein the extension overlaps a surface of the insulating frame facing the susceptor.

11. (currently amended) A chemical vapor deposition apparatus comprising: a chamber having an inner space and top, bottom, and side wall; a susceptor disposed in the chamber and supporting a substrate; a diffuser partitioning the inner space of the chamber into first and second partitions and having an extension of an "L" shape extended out from a boundary, wherein the extension of the diffuser is exposed to the inner space of the chamber; and

an insulating frame disposed between the side wall of the chamber and the diffuser, said insulating frame being disposed on an upper side of the extension of the diffuser and extending to and contacting the side wall of the chamber.

12. (previously presented) The apparatus of claim 11, wherein the extension overlaps a surface of the insulating frame facing the susceptor.